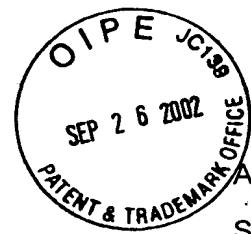


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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: NAKANO, et al.  
Serial No.: 10/075,244  
Filed: February 15, 2002  
For: METHOD AND APPARATUS FOR PLASMA PROCESSING  
Group: 1762  
Examiner: Unassigned

RECEIVED  
SEP 27 2002  
TC 1700

INFORMATION DISCLOSURE STATEMENT  
UNDER 37 CFR 1.97 & 1.98

Assistant Commissioner for Patents  
Washington, D.C. 20231

September 26, 2002

Sir:

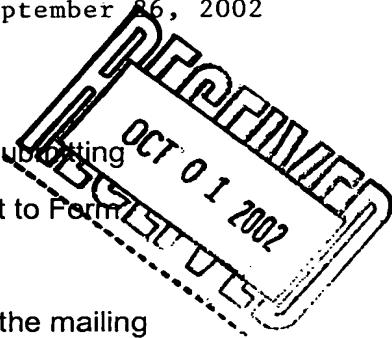
In the matter of the above-identified application, applicants are submitting herewith a copy of the documents listed in the attached form equivalent to Form PTO-1449 for the Examiner's consideration.

This information disclosure statement is being submitted before the mailing date of a first office action on the merits.

On information and belief, I hereby certify that each item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.

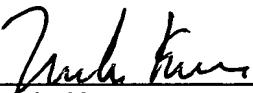
To the extent that, the documents listed on the attached form equivalent to Form PTO-1449, are not in the English language, the requirement of 37 CFR 1.98(a)(3) for a concise explanation of the relevance is satisfied by English language abstracts.

It is respectfully requested that this information disclosure statement be considered by the Examiner.



Please charge any shortage in the fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account No. 01-2135 (501.41175X00) and please credit any excess fees to such deposit account.

Respectfully submitted,



Melvin Kraus  
Registration No. 22,466  
ANTONELLI, TERRY, STOUT & KRAUS, LLP

MK/nbf  
Attachments  
(703) 312-6600